



Microsystems Based on Wide Band Gap Materials for Future Space Transmitting Ultra Wideband Receiving Systems

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SATURNE: Microsystems Based on Wide Band Gap Materials for Future Space Transmitting Ultra Wideband Receiving Systems

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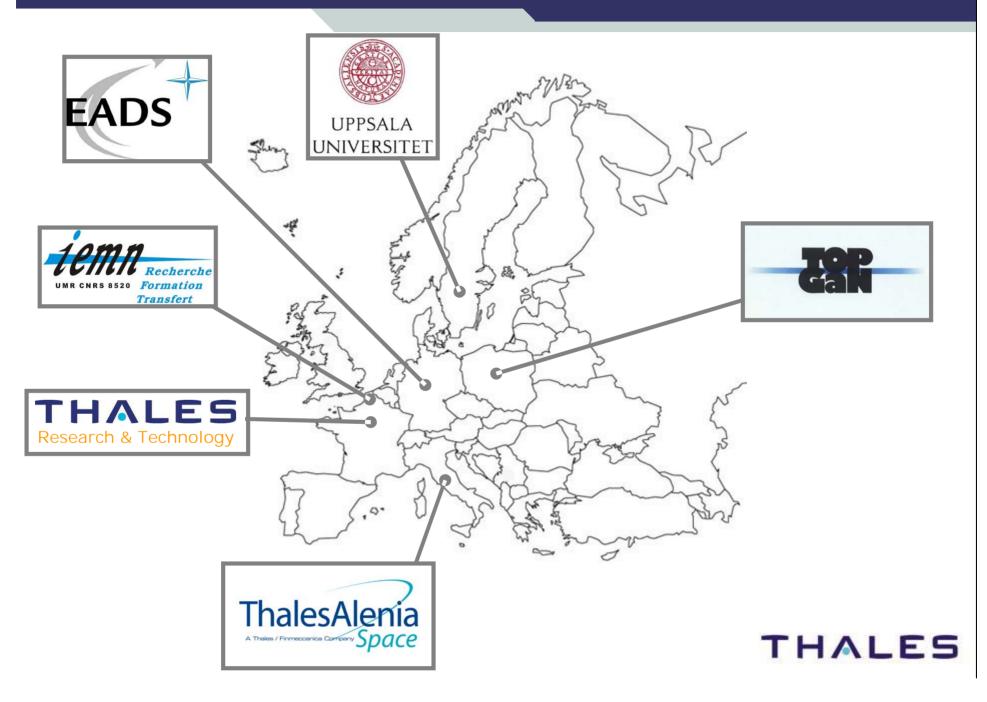
FP7-SPACE-2009-1

Work programme topics addressed

- Activity 9.2 Strengthening the foundations of Space science and technology
- Area 9.2.2 Research to support space transportation and key technologies
- u SPA.2009.2.2.01 Space technologies

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Consortium



Integration of WBG devices and RF-MEMS

- **u** Monolithic integration approach
- **u** Hybrid integration approach
- **u** Hybrid and monolithic integration approaches

1st demonstrator: Smart active antenna based on WBG devices and RF-MEMS

2nd demonstrator: A miniaturized reconfigurable front-end

3rd demonstrator: Re-configurable frequency-agile T/R module



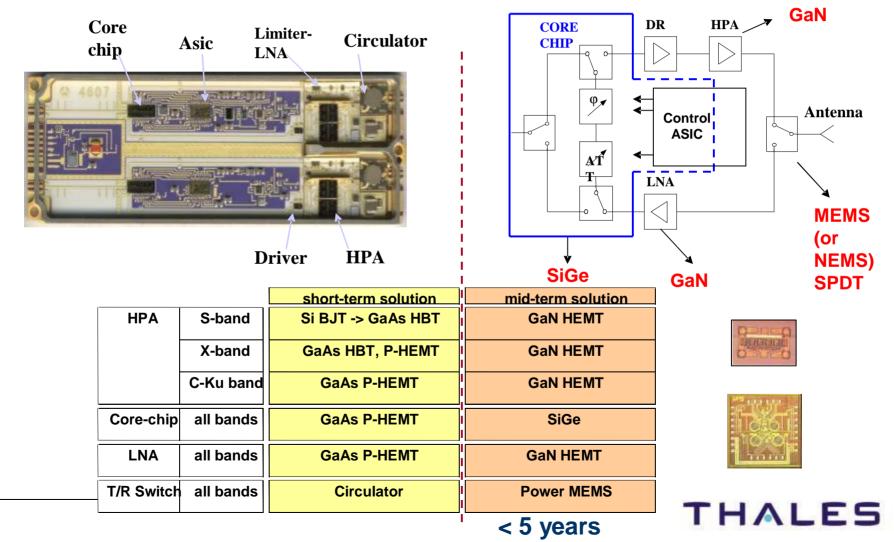
Monolithic integration approach

- Assessment and compatibility of RF-MEMS fabrication process and GaN technology
- An elementary device, a GaN based RF-MEMS switch, will be developed with the following specifications:
 - £ Frequency range: 2-20 GHz
 - £ Power handling: 10 W (40 dBm)
 - £ Isolation: -20 dB
 - \in Insertion loss: -0.4 dB
- GaN-based-MEMS-RF subsystems: Single Pole Double Throw (SPDTs)
- Feasibility of a production process of these components compatible with the integration of both MMICs and RF-MEMS functions onto the same substrate will be evaluated

▷ 1st demonstrator: Smart active antenna based on WBG devices and RF-MEMS THALES

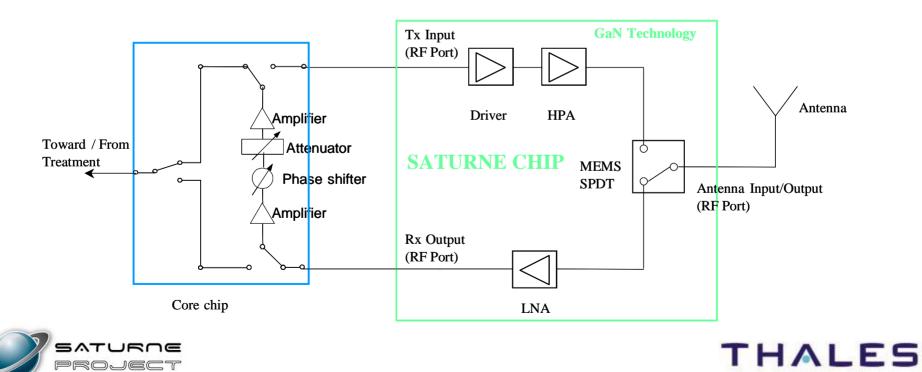
Context, SoA & Goals

u GaN devices for microwave applications



Demonstrator #1 (Thales Research & Technology) High Power T/R module Monolithic integration of GaN technologies

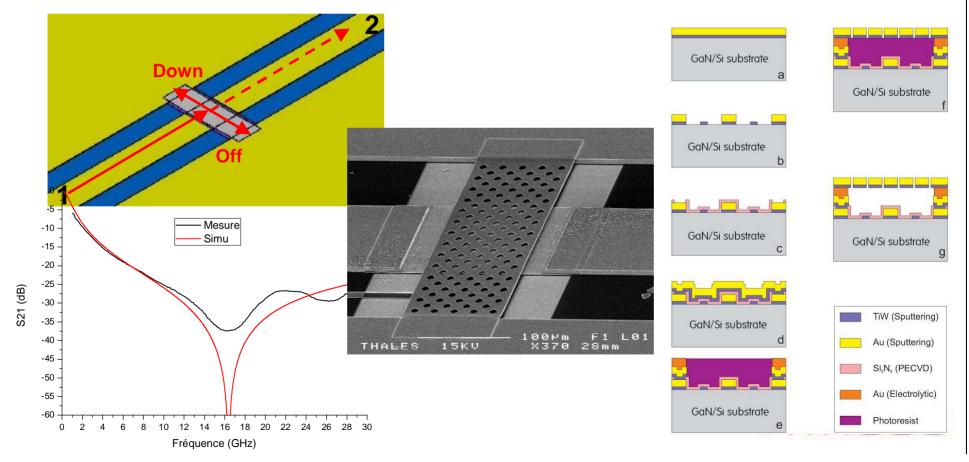
- **GaN-based HPA & LNA (20W X-Band)**
- **GaN-based RF-MEMS SPDT**



Monolithic integration of RF-MEMS on GaN

U Shunt RF-MEMS on GaN/Si (Dielectric: PZT or TiO2)

Next step: integration with GaN HEMT



Hybrid integration approach

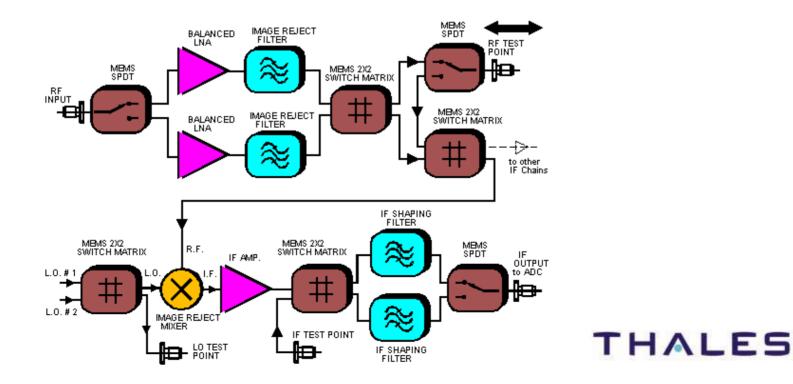
- Feasibility and performance of re-configurable RF-MEMS based matching networks for GaN power and low-noise transistors by using a hybrid integration approach of both technologies
- RF-MEMS switches will be integrated on LTCC multilayer substrates
 - \in RF-MEMS switches on LTCC
 - £ RF-MEMS SPDTs and 2x2 switch matrices on LTCC

Demonstrator #2 (Thales Alenia Space Italy) Multi-band re-configurable receiver Hybrid integration on LTCC

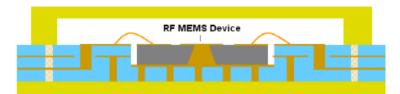
u GaN amplifiers on LTCC (C- & X-band)

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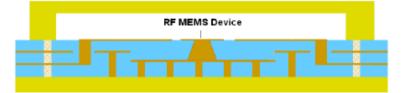
u RF-MEMS SPDT & 2x2 matrix on LTCC substrates

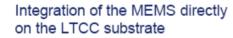


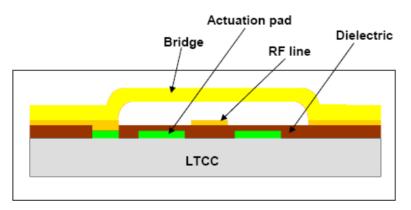
RF-MEMS on LTCC

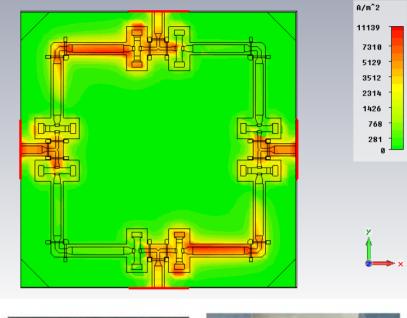


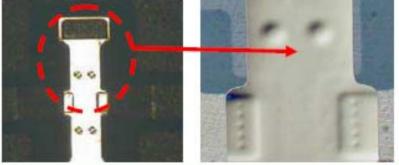
Silicon MEMS chip glued in a LTCC package with internal wire transitions











The electrostatic actuation of the bridge is obtained by means of two resistive metallic pads (made of NiCr or TaN). The actuation pads are covered with a dielectric layer (polyimide).

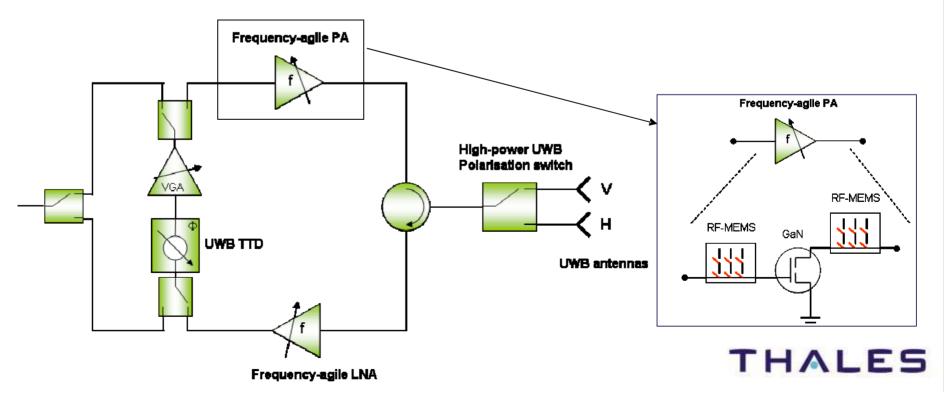
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Hybrid and monolithic integration approaches

- Re-configurable RF-MEMS based matching networks and highpower SPDT switches will be designed and manufactured on Silicon and on GaN
- These circuits will then be integrated with the GaN high-power and low-noise transistors on a LTCC RF-board
- Ultra-high performance true-time-delay (TTD) units

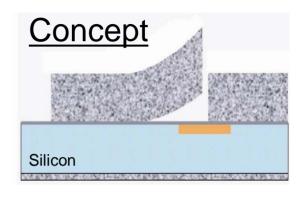
Demonstrator #3 (EADS) Reconfigurable frequency-agile T/R-module Hybrid integration on multilayer LTCC board

- GaN-based amplifiers (from L- to Ku-band)
- Si-based RF-MEMS SPDT



RF-MEMS switches on Si

- high-resistivity silicon substrate thermally grown silicon oxide Implantation layer for capacitive coupling only 3 lithography process steps
- substrate thickness: 100um
 black parts are bended upwards
 design focus on low-frequency
 behaviour
- Frequency-range: 1.8 10GHz Insertion loss: < -0.6dB Isolation:> -26dB



Fabricated switch



Measurement results

